

US00D860419S

(12) **United States Design Patent** (10) **Patent No.:** **US D860,419 S**
Kosugi et al. (45) **Date of Patent:** **** Sep. 17, 2019**

(54) **ELECTRIC FURNACE FOR SUBSTRATE PROCESSING APPARATUS**

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JP 1582475 S 7/2017

(**) Term: **15 Years**

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(21) Appl. No.: **29/656,364**

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(22) Filed: **Jul. 12, 2018**

(57) **CLAIM**

The ornamental design for an electric furnace for substrate processing apparatus, as shown and described.

(30) **Foreign Application Priority Data**

DESCRIPTION

Feb. 27, 2018 (JP) 2018-004005

(51) **LOC (12) Cl.** **23-03**

(52) **U.S. Cl.**
USPC **D23/329**

(58) **Field of Classification Search**
USPC D23/314, 318, 319, 323, 329, 341;
D13/112, 179; D15/144, 144.1, 144.2
CPC H01L 21/67109; H01L 21/67098; H01L
21/324

See application file for complete search history.

FIG. 1 is a front, bottom and left side perspective view of an electric furnace for substrate processing apparatus showing our new design;

FIG. 2 is a front elevational view thereof;

FIG. 3 is a right side elevational view thereof;

FIG. 4 is a left side elevational view thereof;

FIG. 5 is a rear elevational view thereof;

FIG. 6 is a top plan view thereof;

FIG. 7 is a bottom plan view thereof.

FIG. 8 is a cross-sectional view take along line 8-8 in FIG. 2 thereof; and,

FIG. 9 is an enlarged portion view taken along line 9-9 in FIG. 2.

The dashed-dot-dashed lines represent the boundary lines of the claimed design.

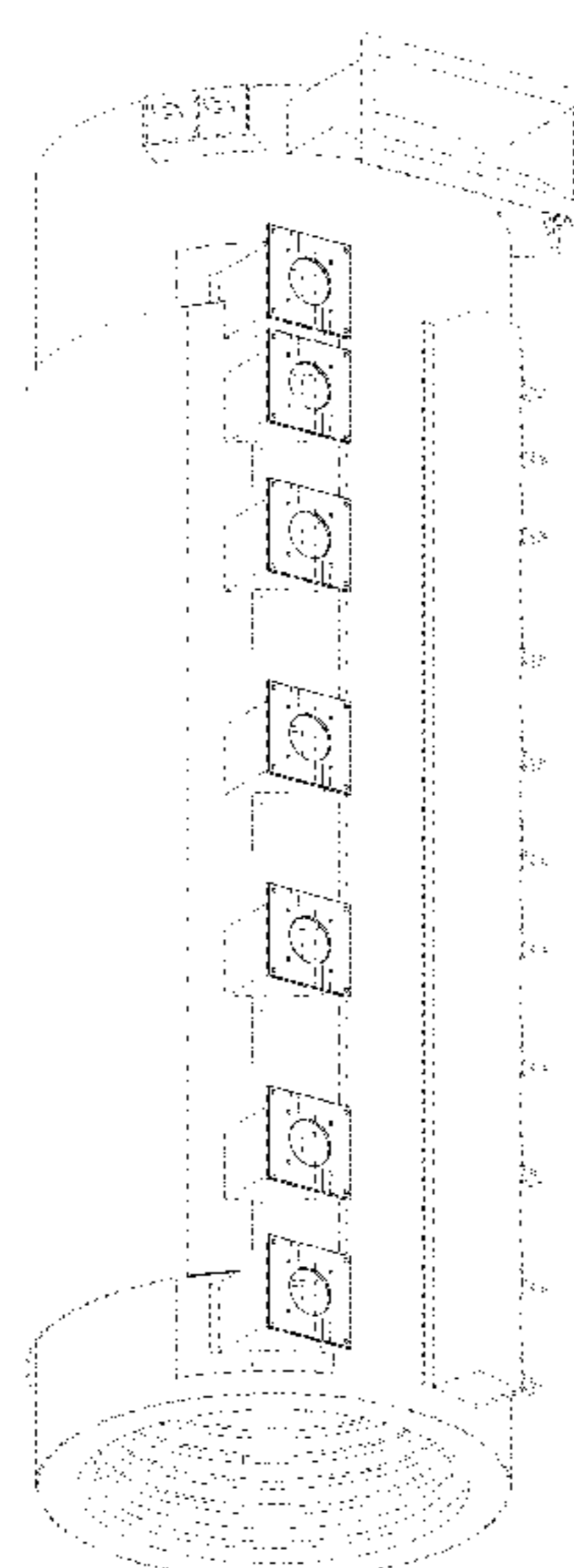
The broken lines shown in the drawings represent portions of the electric furnace for substrate processing apparatus that form no part of the claimed design.

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1 Claim, 8 Drawing Sheets



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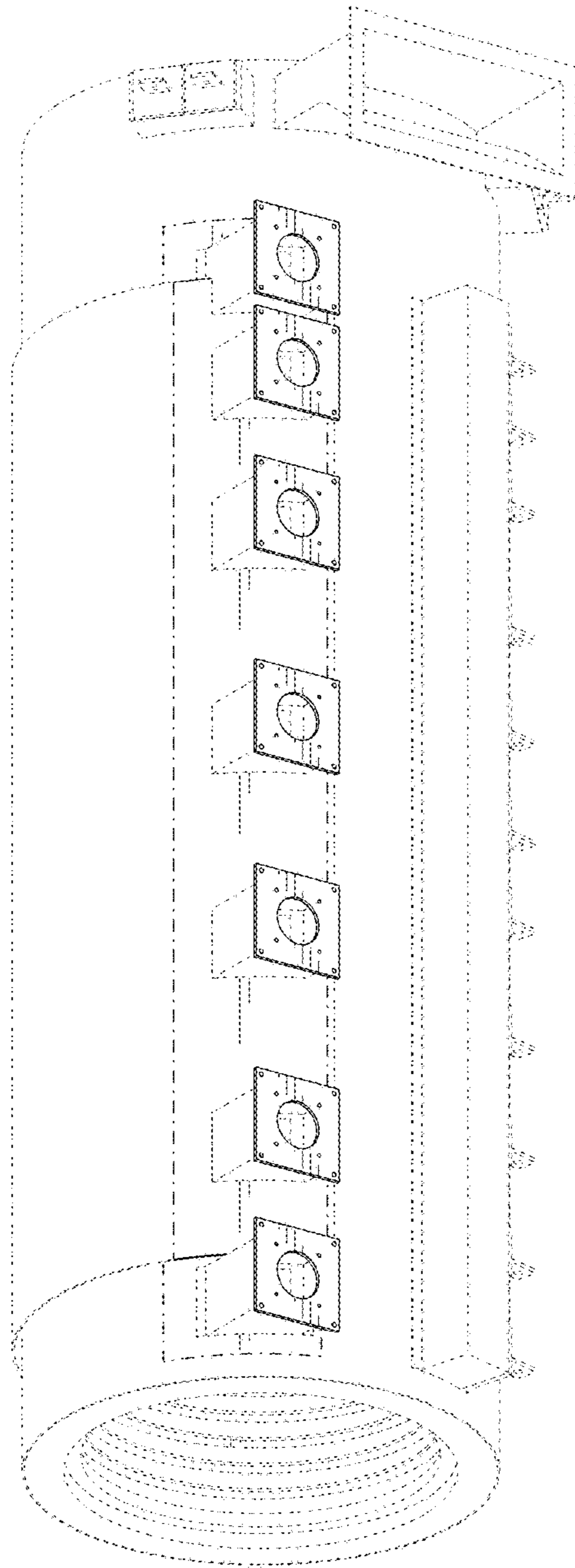


FIG. 1

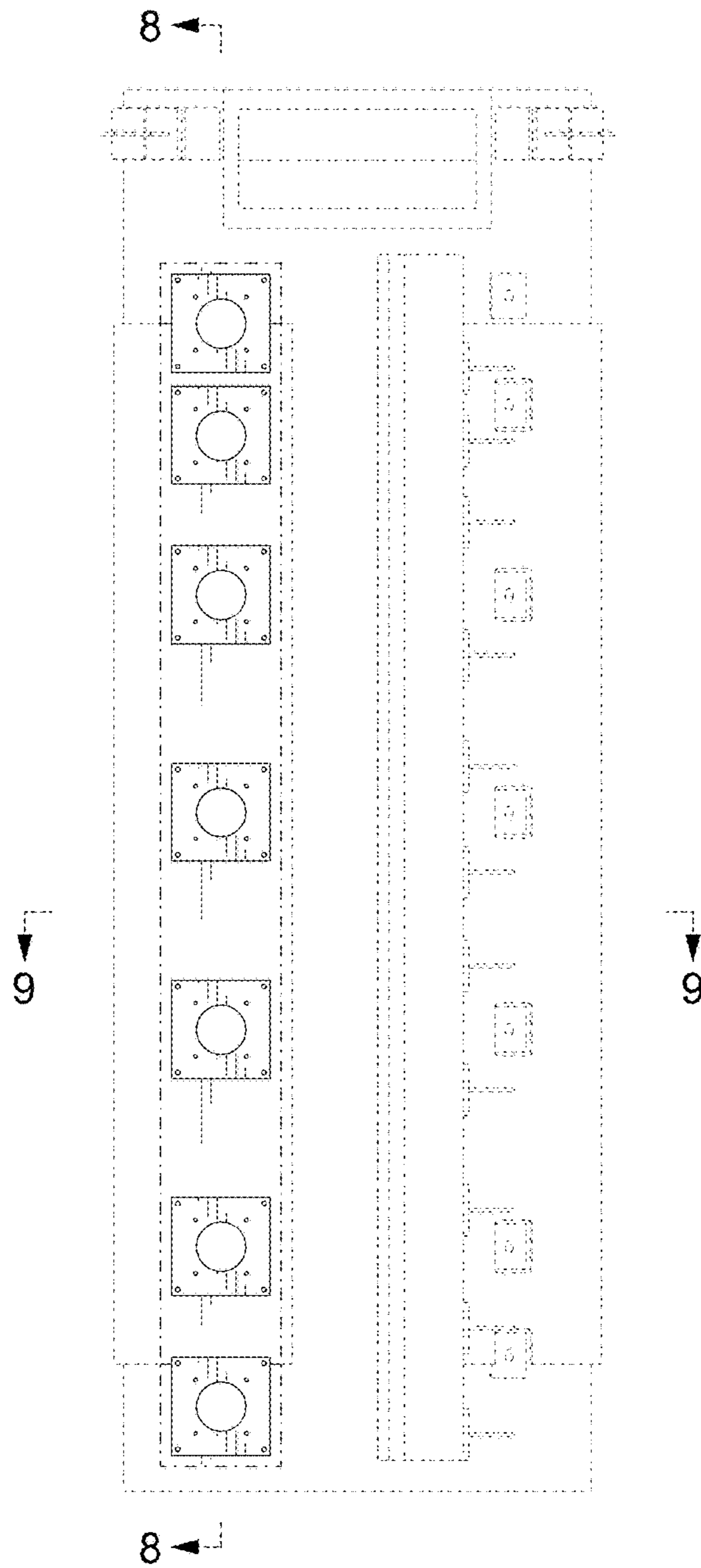


FIG. 2

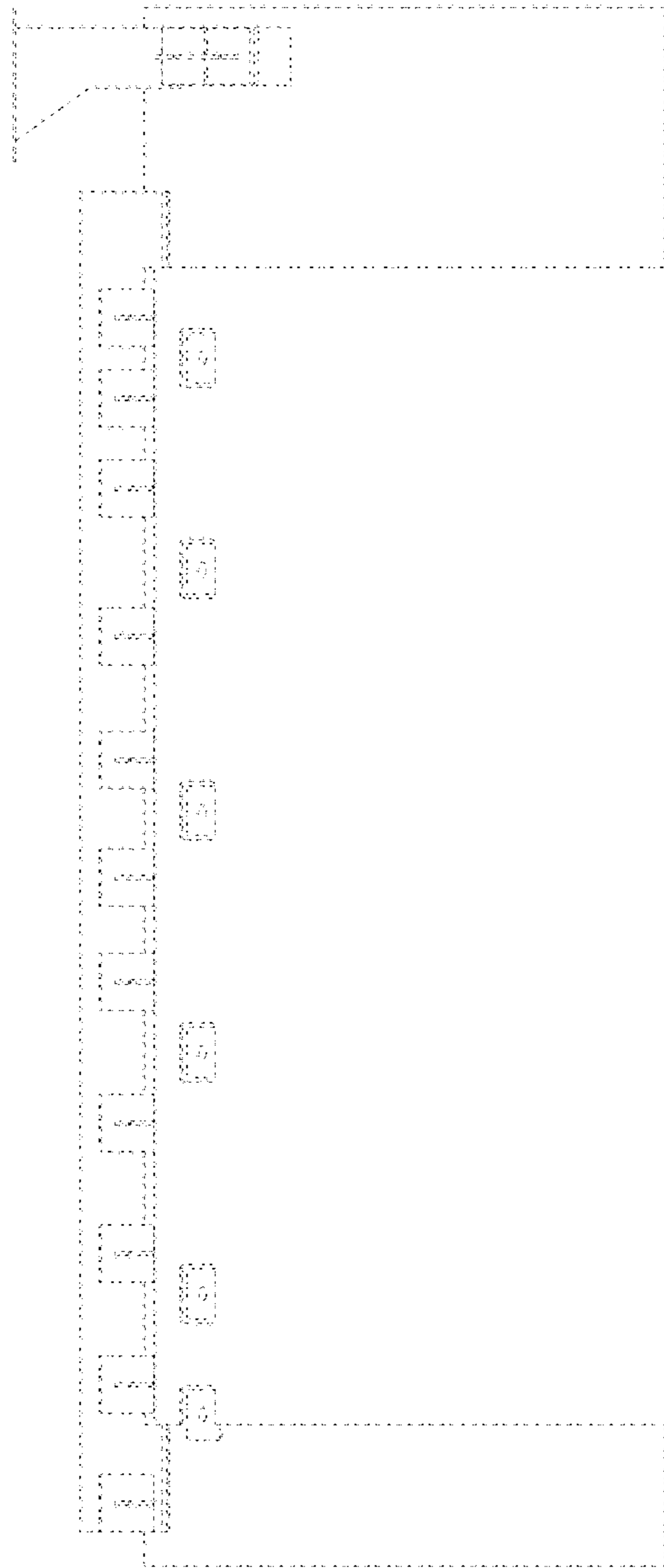


FIG. 3

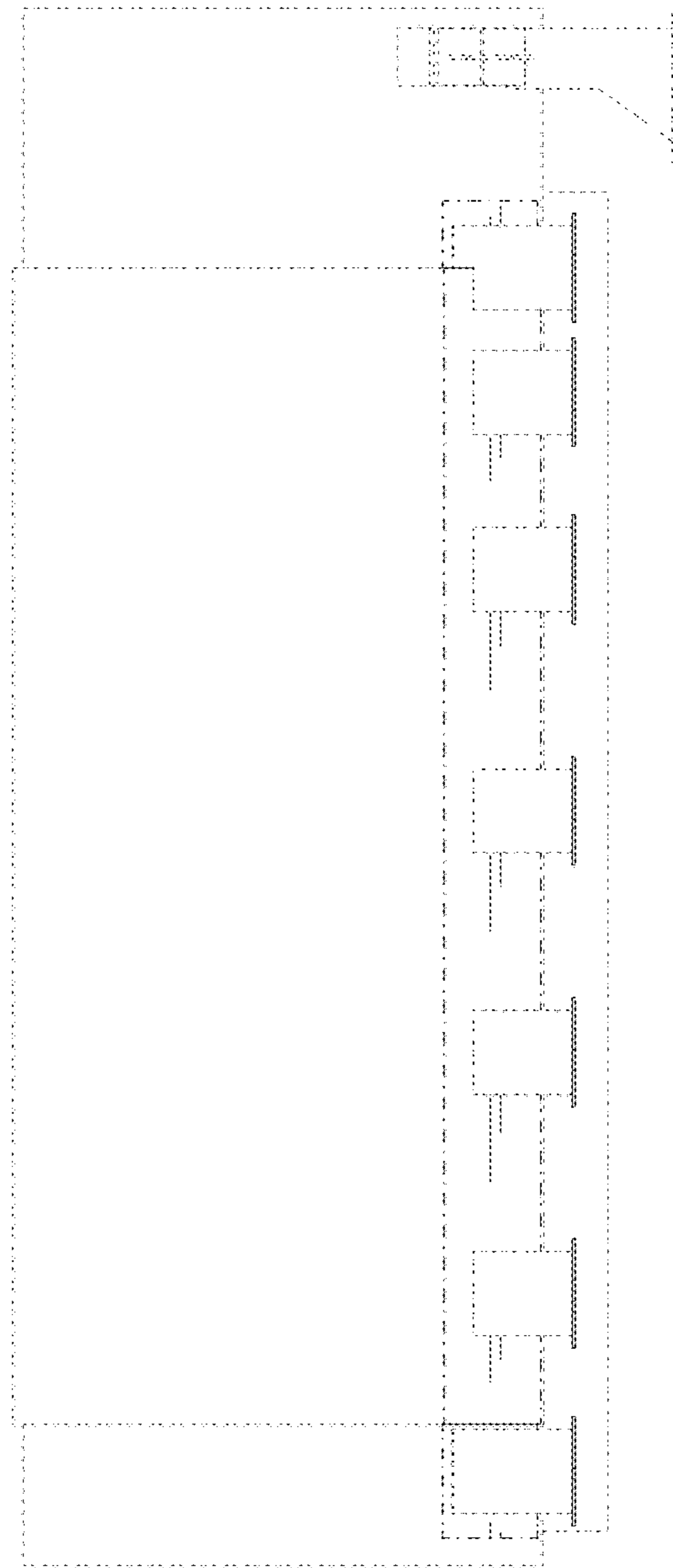


FIG. 4



FIG. 5

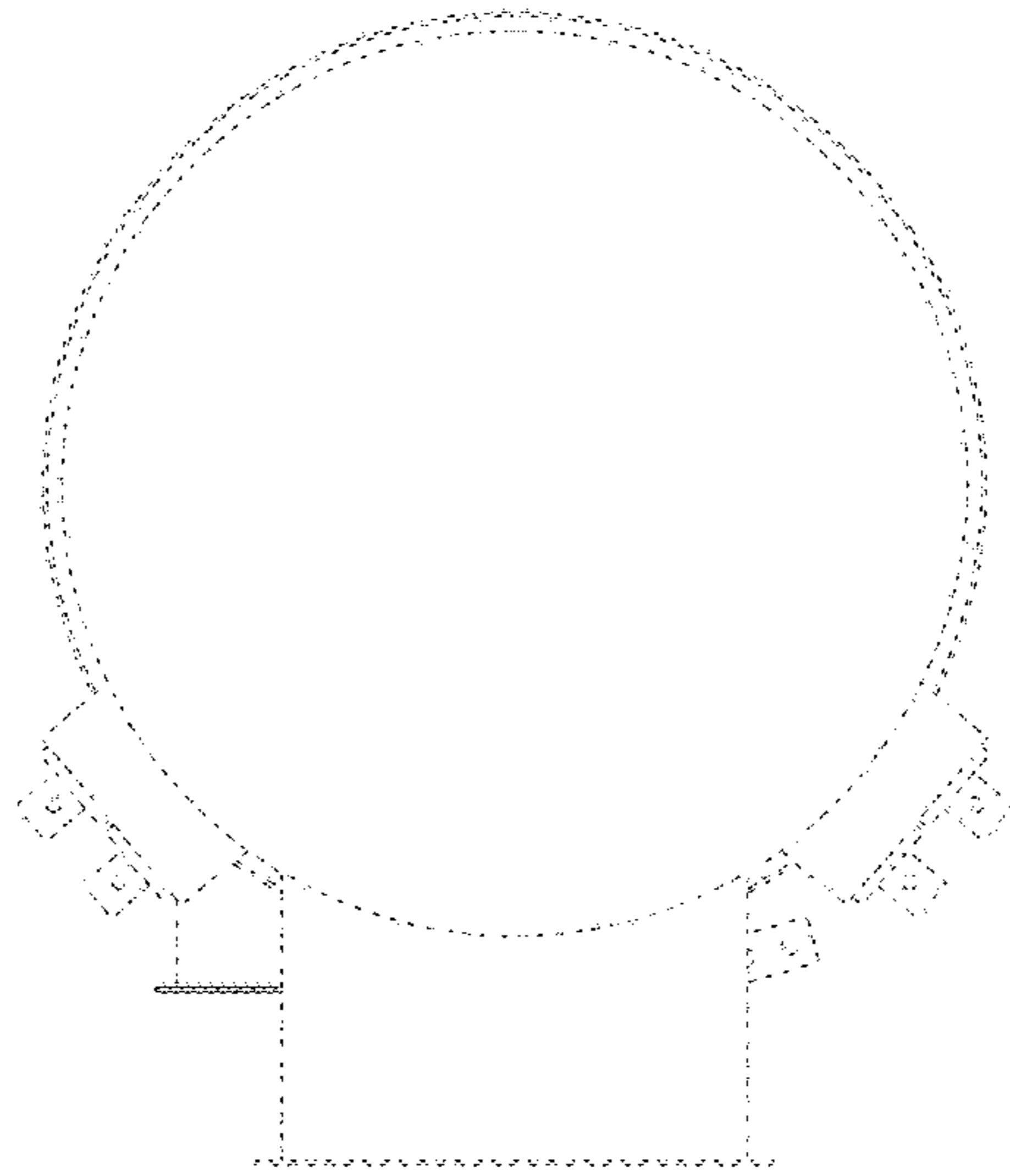


FIG. 6

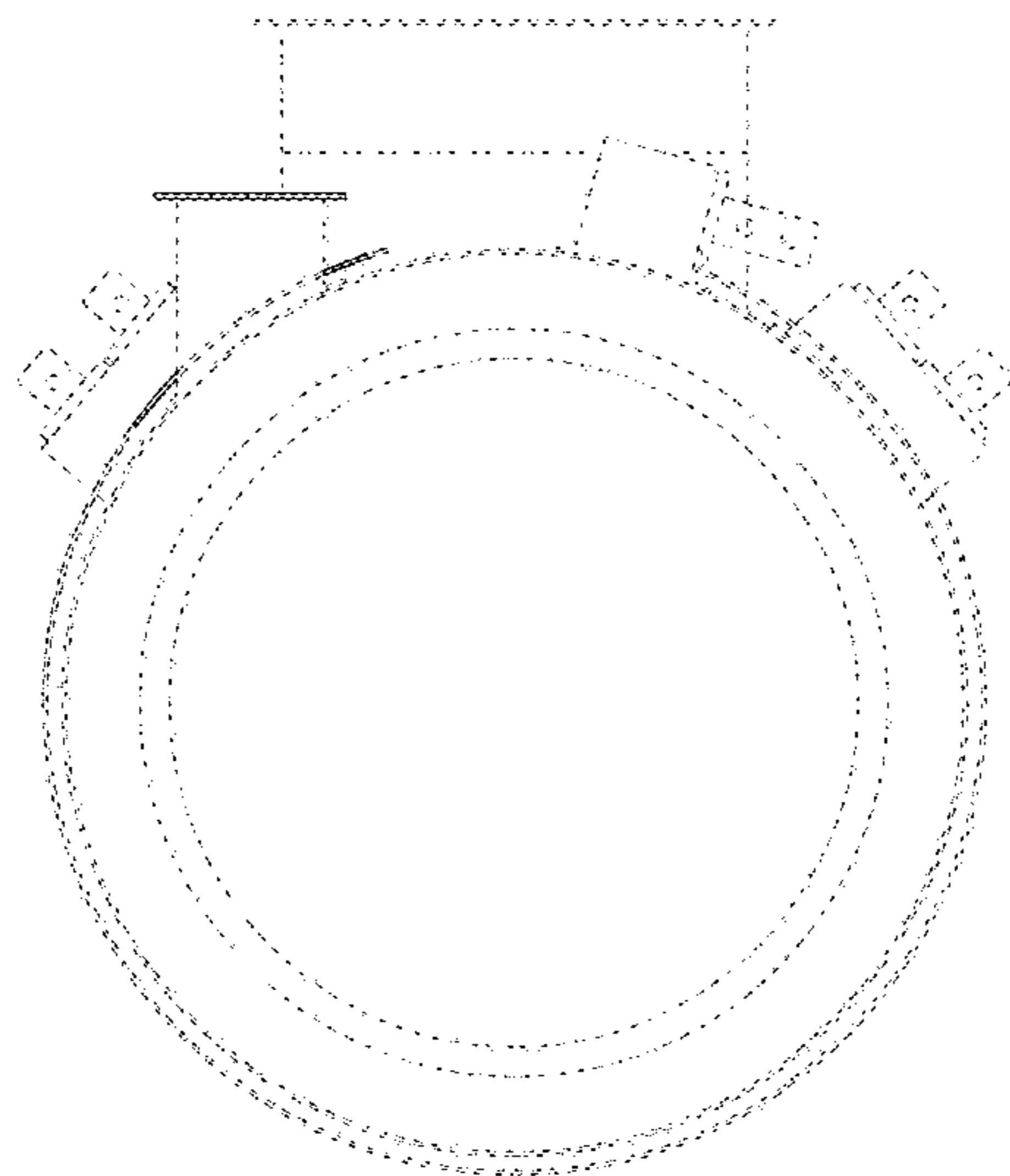


FIG. 7

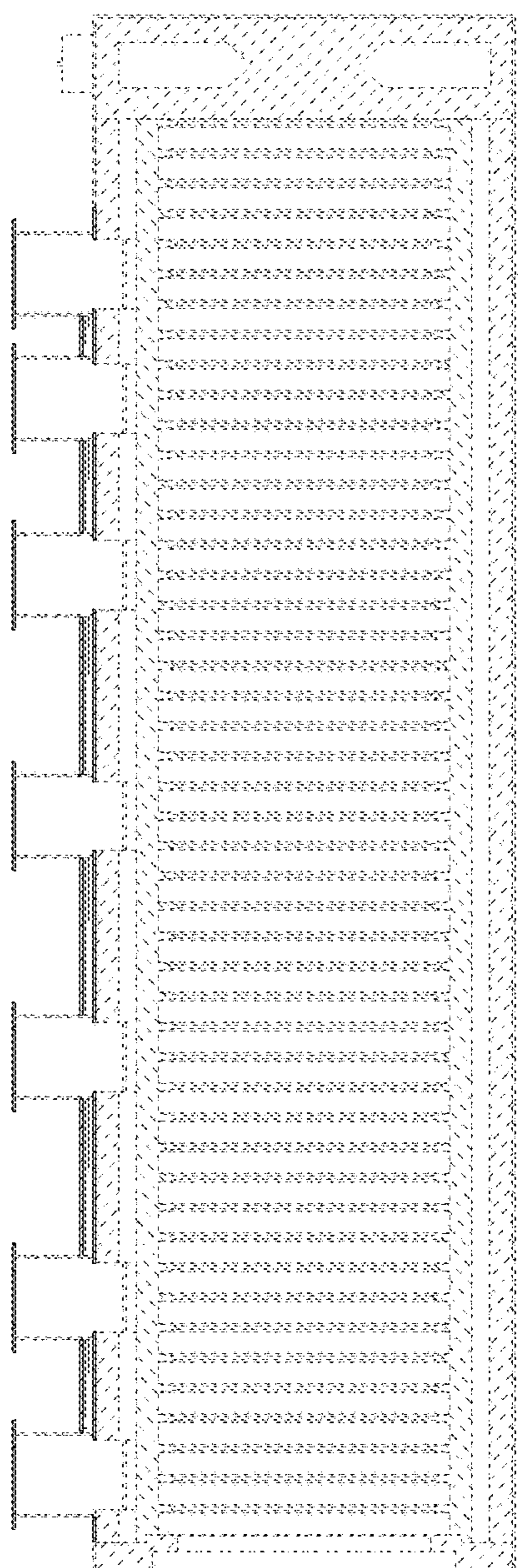


FIG. 8

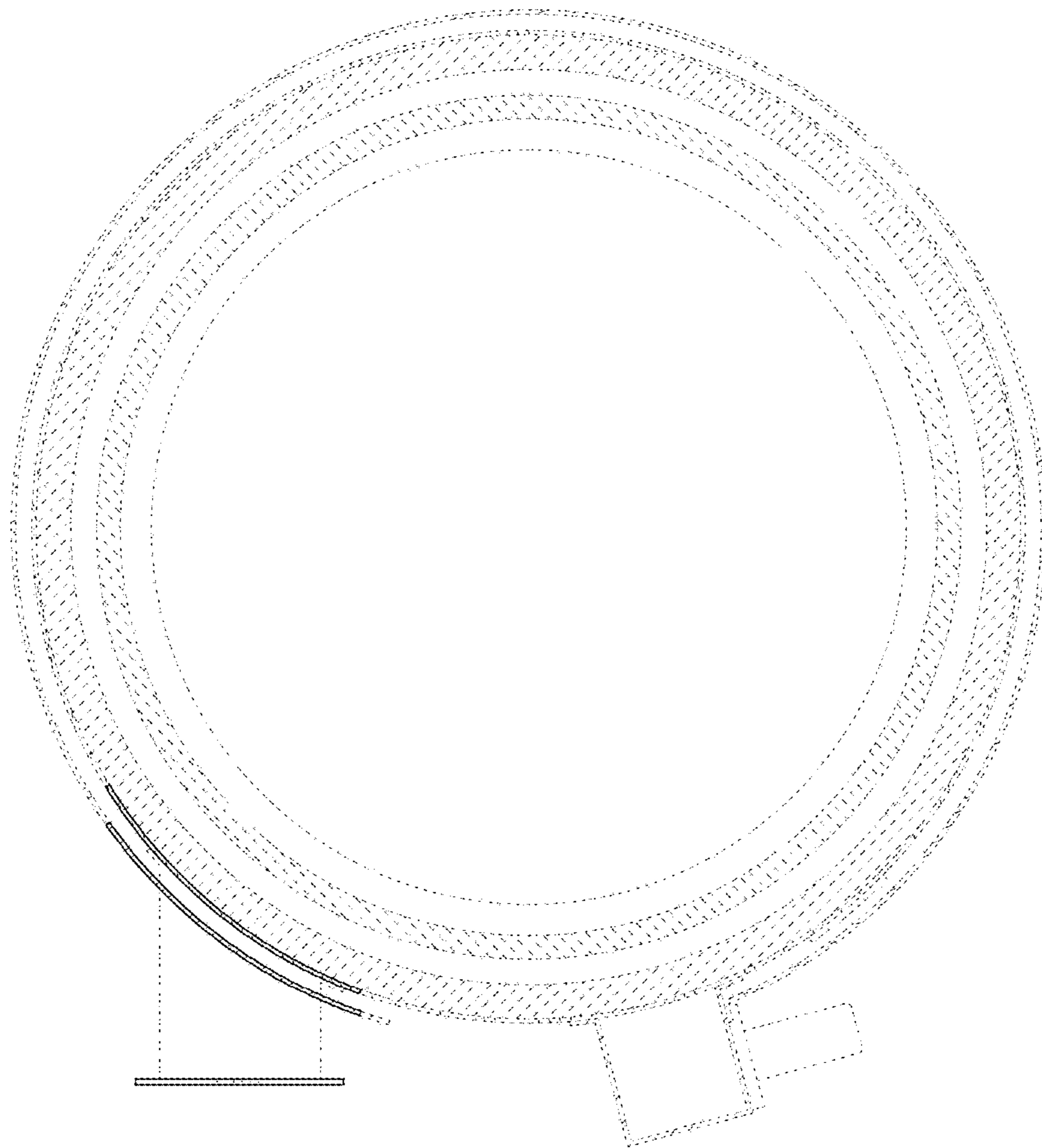


FIG. 9